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**Determination of collisional quenching rate coefficient of  $N_2(A^3\Sigma_u^+)^1$**  YUUSUKE KOIZUMI, SUSUMU SUZUKI, HARUO ITOH, Chiba Institute of Technology — We have previously determined the collisional quenching rate coefficient of  $N_2(A^3\Sigma_u^+)$  by an air pollutant gas [1-4]. In this paper we report the collisional quenching rate coefficient  $k'$  of  $N_2(A^3\Sigma_u^+)$  by *p*-xylene ( $C_8H_{10}$ ), which was determined to be  $(6.5\pm 0.9)\times 10^{-9}$  cm<sup>3</sup>/s. In addition, through repeated experiments it was found that by-products of *p*-xylene were deposited on the cathode, similarly to the cases of *m*-xylene and *o*-xylene previously reported [4], and then the current-voltage curves consistently shifted to a higher- $E/p_0$  region. To clarify the reason for this behavior, we confirmed by Auger electron spectroscopy (AES) and Fourier transform infrared spectroscopy (FTIR) that these changes in the current-voltage curves were caused by the deposition of a thin film of by-product of decomposed xylene on the cathode surface. According to the results of AES, C atoms were detected in a sample exposed to an electrical discharge, and we confirmed that the deposit of C was thickest in the case of electrical discharge in *p*-xylene. According to the results of FTIR, it was found that CH<sub>2</sub> and CH were obtained from the deposition of *p*-xylene.

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